

The Examiner is respectfully requested to amend the above-identified application as follows.

IN THE CLAIMS:

For the Examiner's convenience, all of the pending Claims 1-11, whether amended or not, are set forth below.

Please amend Claims 1-8 to read as follows. A marked-up copy of Claims 1-8, showing the changes made thereto, is attached.

1. (Amended) A manufacturing method of an electron-emitting device comprising the steps of:

disposing an electrically conductive member having a gap on a substrate; and

applying a voltage to said electrically conductive member while irradiating at least said gap with an electron beam from electron emitting means disposed apart from said electrically conductive member in an atmosphere comprising a carbon compound.

2. (Amended) A manufacturing method of an electron-emitting device comprising the steps of:

disposing first and second electrically conductive members on a substrate with a gap interposed; and

applying a voltage to said first and second electrically conductive members while irradiating at least said gap with an electron beam from electron emitting means

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disposed apart from said electrically conductive members in an atmosphere comprising a carbon compound.

3. (Amended) A manufacturing method of an electron-emitting device comprising the steps of:

disposing an electrically conductive member having a gap on a substrate; and

irradiating at least said gap with an electron beam from electron emitting means disposed apart from said electrically conductive member in an atmosphere comprising a carbon compound within a period where a voltage is applied to said electrically conductive member.

4. (Amended) A manufacturing method of an electron-emitting device comprising the steps of:

disposing first and second electrically conductive members on a substrate with a gap interposed; and

irradiating at least said gap with an electron beam from electron emitting means disposed apart from said electrically conductive members in an atmosphere comprising a carbon compound within a period where a voltage is applied to said first and second electrically conductive members.

5. (Amended) The manufacturing method of an electron-emitting device according to claim 1 or 3, wherein said electrically conductive member having said gap is an

electrically conductive film which connects a pair of electrodes to each other and has said gap in a portion of the electrically conductive film.

6. (Amended) The manufacturing method of an electron-emitting device according to claim 2 or 4, wherein said electrically conductive members are a pair of electrodes which are disposed with said gap interposed.

7. (Amended) The manufacturing method of an electron-emitting device according to claim 2 or 4, wherein said electrically conductive members are a first electrically conductive film and a second electrically conductive film which are connected to first and second electrodes disposed apart respectively and are disposed with said gap interposed.

8. (Amended) The manufacturing method of an electron-emitting device according to any one of claims 1 through 4, wherein said applied voltage is a pulse-like voltage.

9. (Not Amended From Prior Version) The manufacturing method of an electron-emitting device according to any one of claims 1 through 4, wherein said electron beam is at an energy level not lower than 1 keV and not higher than 20 keV.

10. (Not Amended From Prior Version) A manufacturing method of an electron source having a plurality of electron-emitting devices, wherein said electron-emitting device is manufactured by the manufacturing method according to any one of claims 1 through 4.

11. (Not Amended From Prior Version) A manufacturing method of an image-forming apparatus having an electron source and an image forming member, wherein said electron source is manufactured by the manufacturing method according to claim 10.

REMARKS

This application has been reviewed in light of the Office Action dated November 7, 2000. Claims 1-11 remain pending in this application.<sup>1</sup> Claims 1-8 have been amended. Those amendments are merely formal in nature, and have not been made for reasons related to patentability. Claims 1-4 are in independent form. Favorable reconsideration is requested.

Initially, the Office Action states that the art cited in the Information Disclosure Statement filed in the Patent and Trademark Office on June 26, 2000 has not been considered by the Examiner, because copies of the art

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1/ Claims 12-14 have been withdrawn from consideration.